

Room Temperature Bonding of Sapphire with Sapphire or Metal Substrates in Air using Au Films



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1. Introduction

- ◇ Sapphire shows various attractive properties
 - High mechanical stress resistance (Young's modulus)
 - High thermal conductivity
 - High chemical stability
 - Wide band transmittance property for optical light.



Figure 1. sapphire substrates

- ◇ Widely used as a wafer material for electronic or light devices, MEMS, watches, and so on.

Room temperature bonding using Au films in air [1,2] was applied for bonding sapphire-sapphire and sapphire-metal substrates.

<Purpose> To develop the potential applications of sapphire using room temperature bonding.

[1] T. Shimatsu and M. Uomoto, ECS Trans., 33, 61 (2010)

[2] H. Kon, M. Uomoto and T. Shimatsu, WaferBond'13, P18, Srockholm (2013)

2. Bonding procedure

Bonding using Au films in air

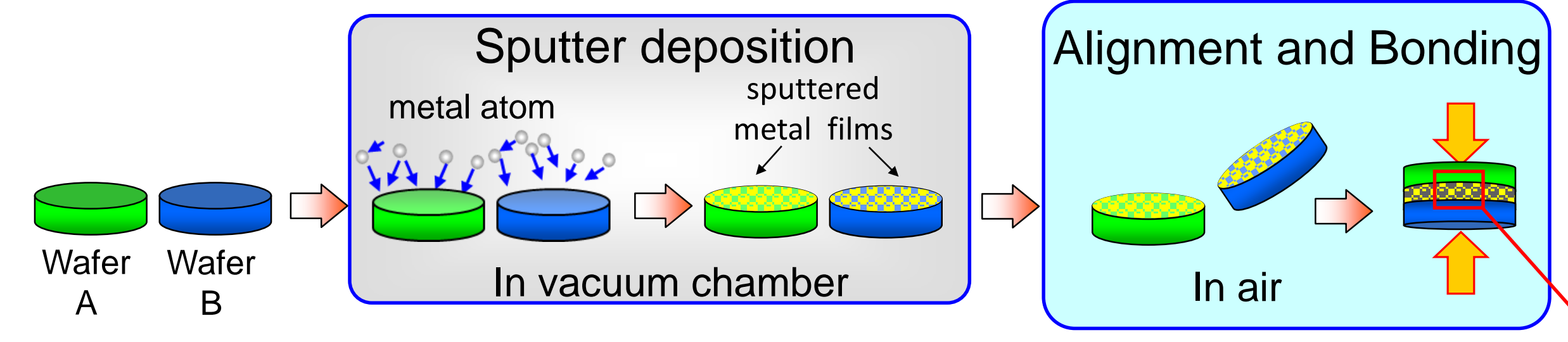


Figure 2. bonding using Au films

- ◇ Au (20, 50, and 75 nm) films with Ti (5 nm) underlayers on both side.

- ◇ Bonding was performed in air at room temperature.

- ◇ Bonding samples: Mirror-polished (CMP) SUS and Al

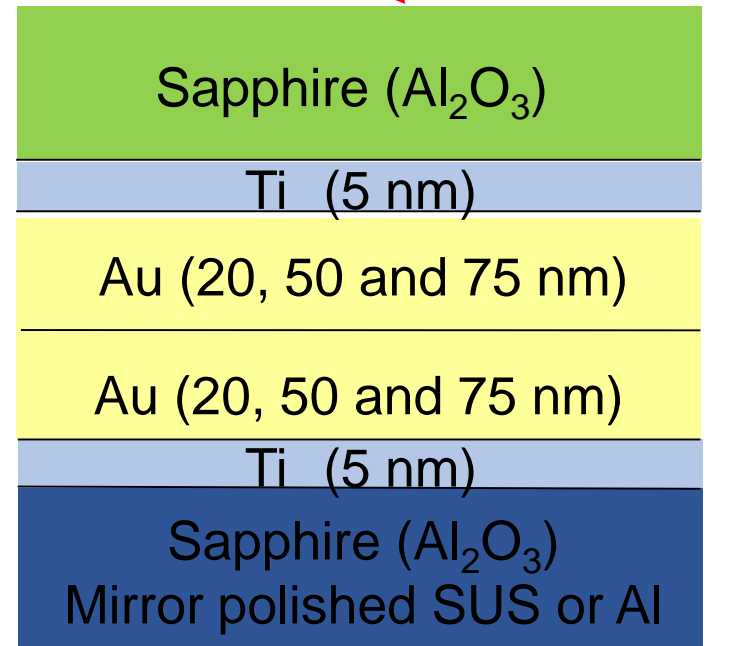


Figure 3. film thickness

3. Bonding of sapphire and sapphire

- ◇ Sapphire substrates were bonded over the entire bonding area.

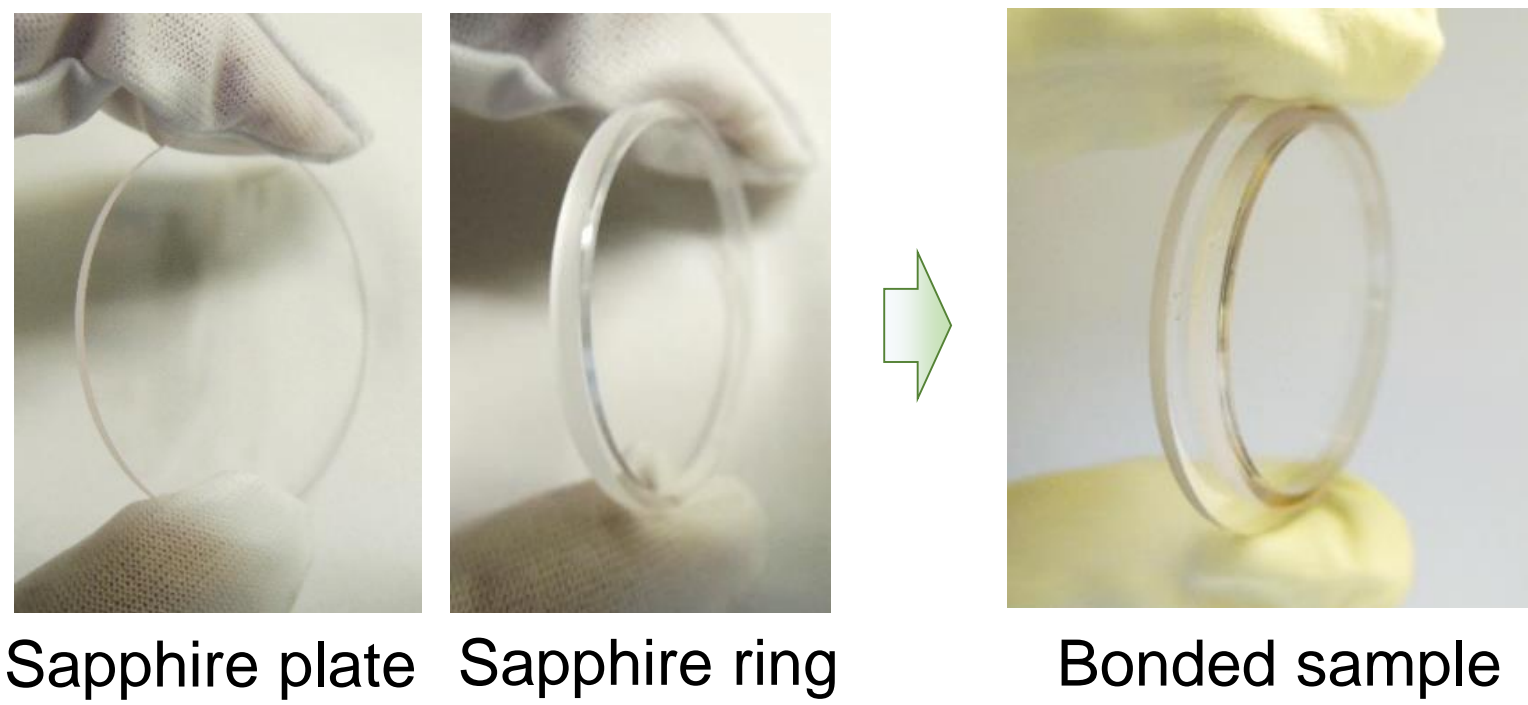


Figure 4. Bonding samples

- Sapphire ring: $\phi 32 \text{ mm} - \phi 29.5 \text{ mm} - 2 \text{ mm}$
- Sapphire plate: $\phi 36 \text{ mm} - 1.2 \text{ mm}$
- Bonded area: 1.23 cm^2
- Loading pressure force: 10-50 MPa

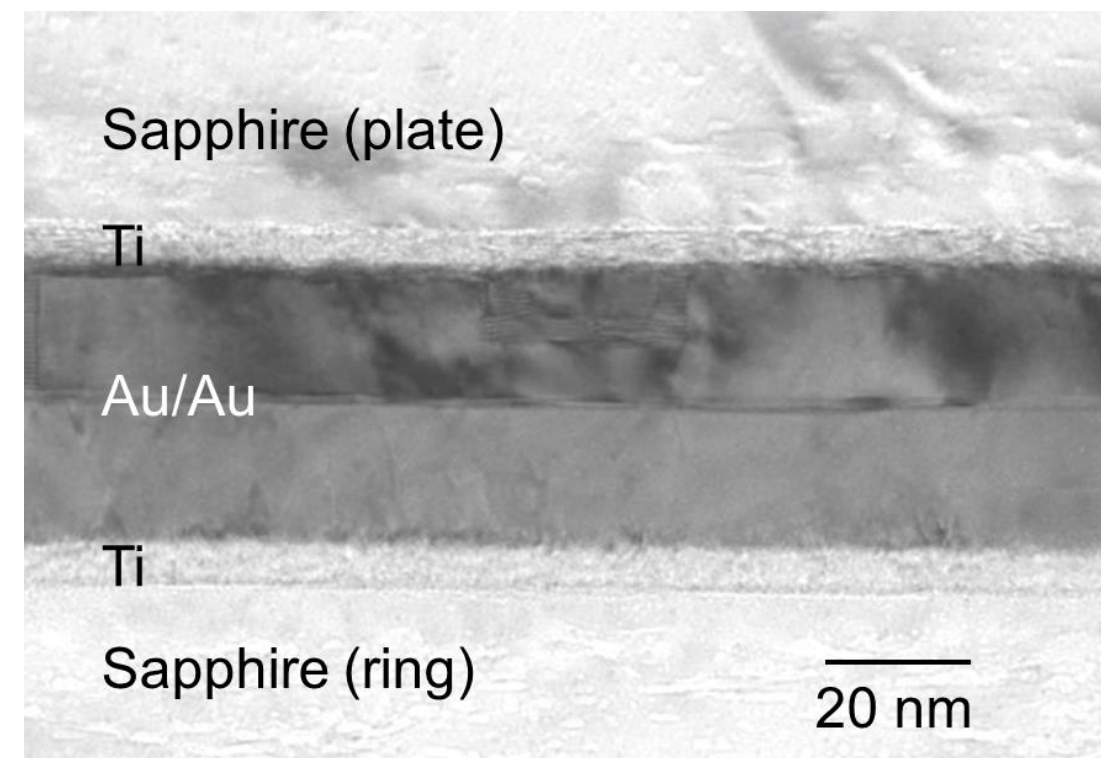


Figure 5. TEM cross-section image (BF)

<Structure (TEM cross-section images)>

- No vacancy was observed at the bonded interface.

<The bonding strength>

- Samples passed the 1 m height drop test using a metal case.
- No problems with water resistant test of 1 MPa.

4. Bonding of sapphire and mirror-polished metal

Bonding of sapphire and SUS was achieved.

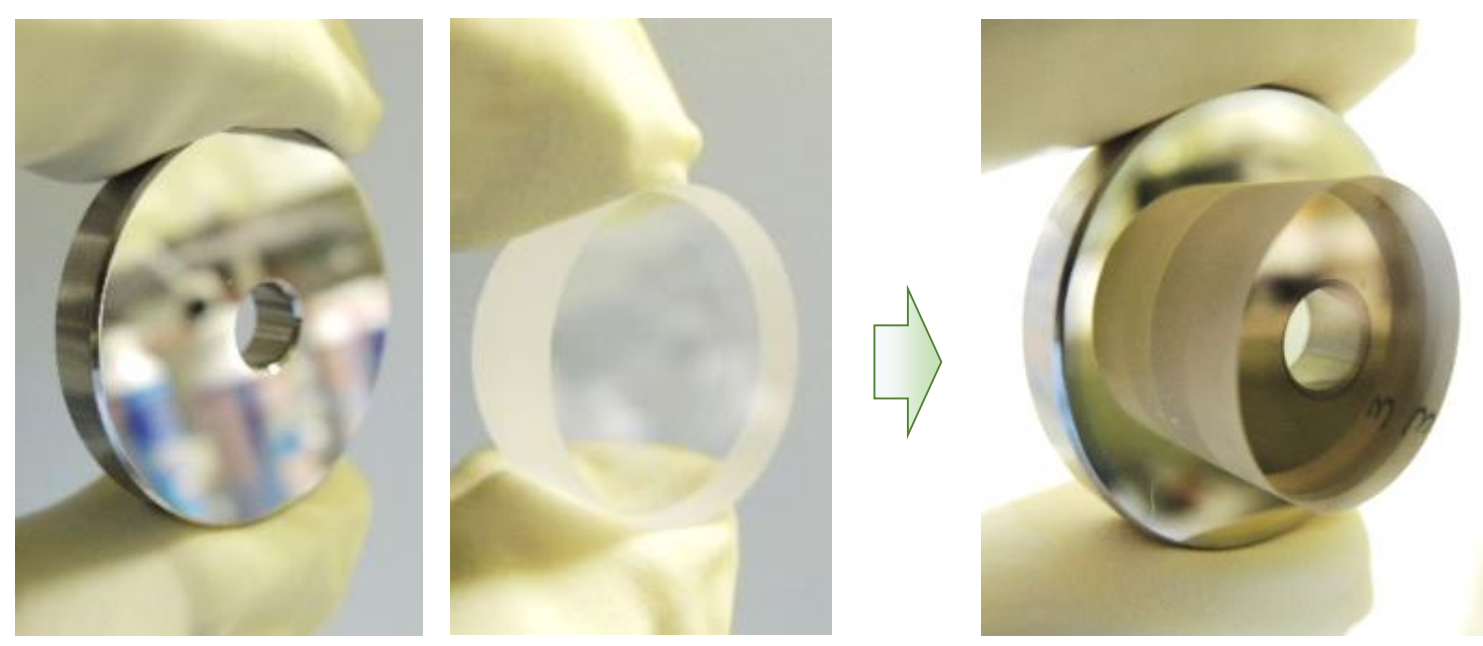


Figure 6. Bonding samples (SUS and sapphire)

- SUS ring $\phi 24 \text{ mm} - \phi 5 \text{ mm} - 4 \text{ mm}$
- Sapphire plate $\phi 15 \text{ mm} - 6 \text{ mm}$
- Bonded area: 1.57 cm^2

A loading pressure force F of 10–50 MPa was necessary for bonding (depending on the surface flatness of these substrates).

<TEM cross-section image>

- ◇ Images show that no interface corresponding to the original Al surfaces is visible; no vacancy is observed.

⇒ Recrystallization occurred at Au/Au bonded interface.

- ◇ BF and HAADF images show that the interface between Ti underlayer and SUS is unclear compared to that on the other side.

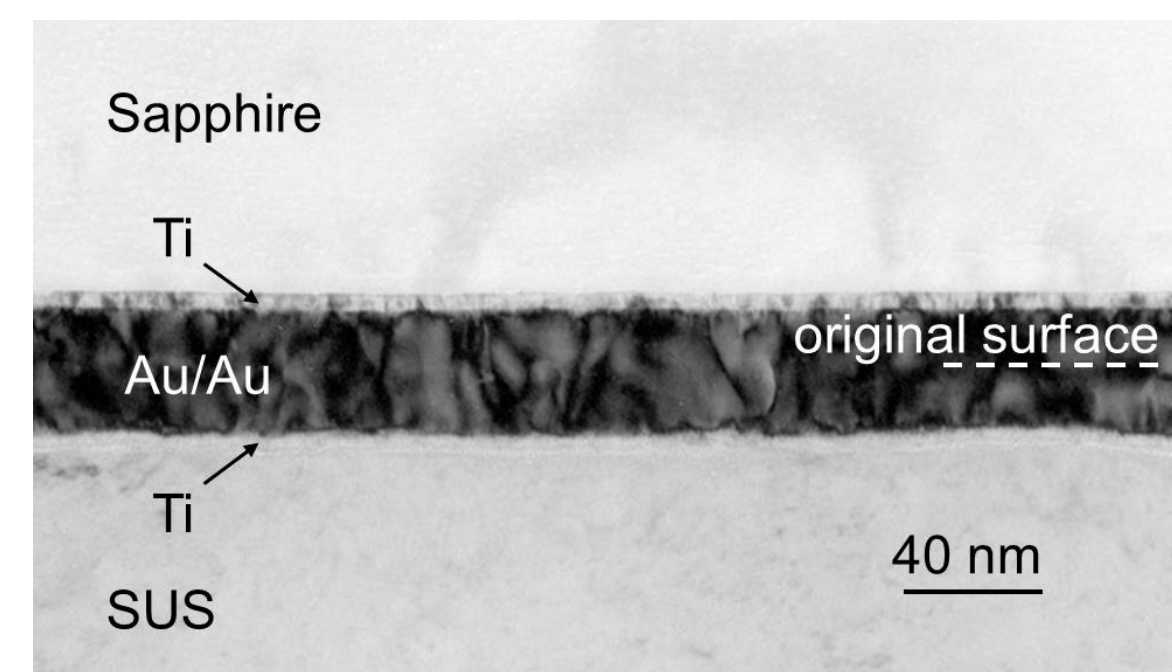


Figure 7. TEM cross-section image (BF)

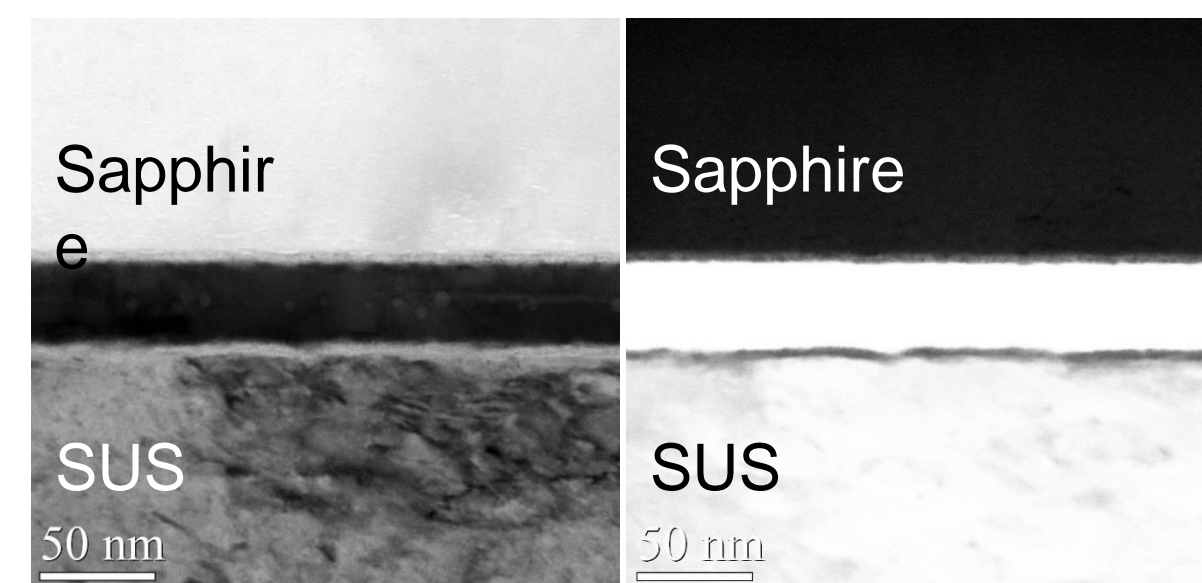


Figure 8. TEM cross-section image (1) BF-STEM (2) HAADF-STEM

<EDX Elemental mapping> Measured elements: Ti, O, Au, Fe, Cr and Ni

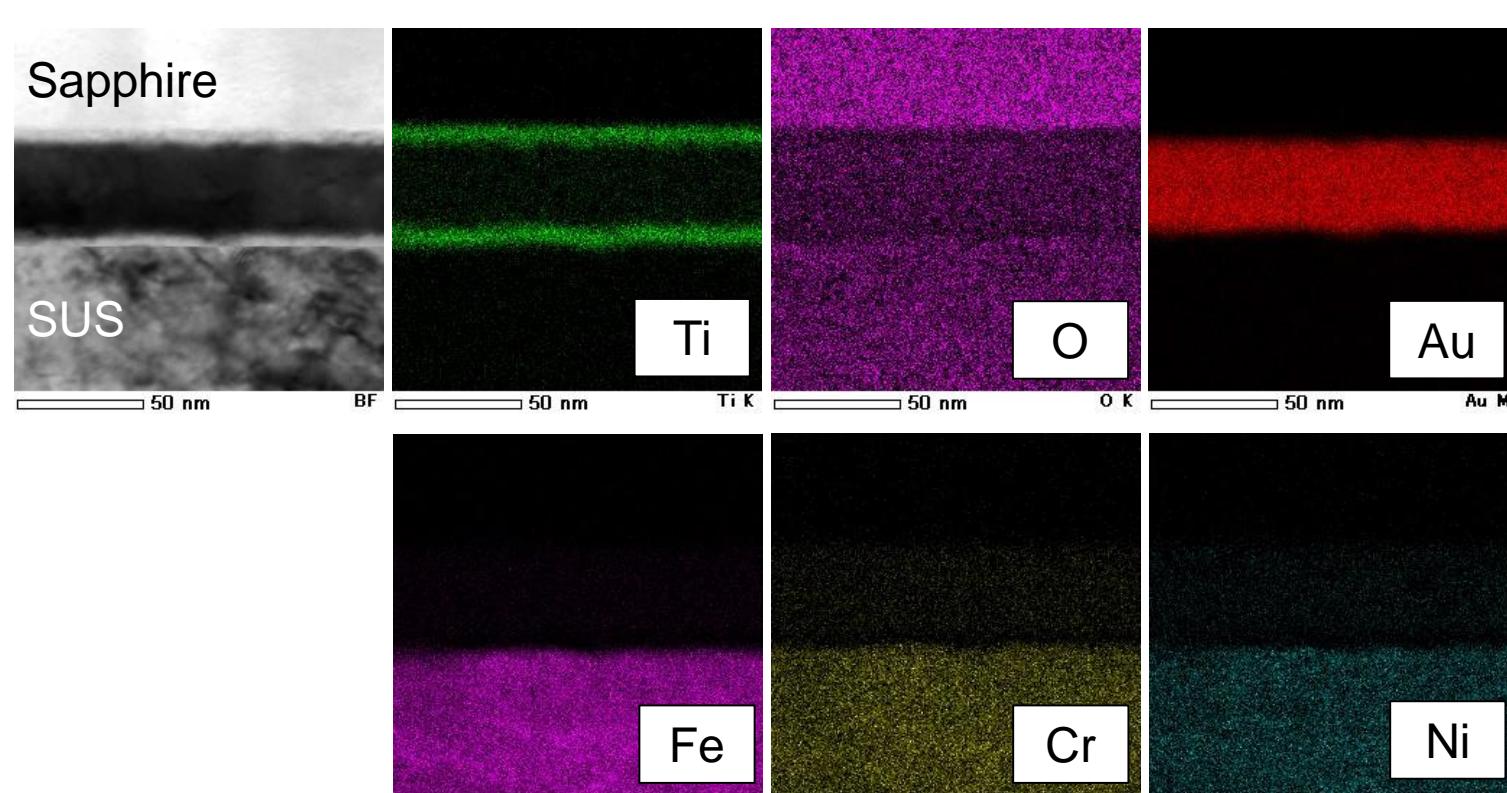


Figure 9. elemental mapping

- ◇ Ti is clearly observed on both side of Au/Au bonded films.

- ◇ Oxygen exists overlapping with Ti underlayers.

⇒ The Ti underlayer is likely to be oxidized.

<EELS spectrum> Comparing Ti layers on both sides to reference TiO₂.

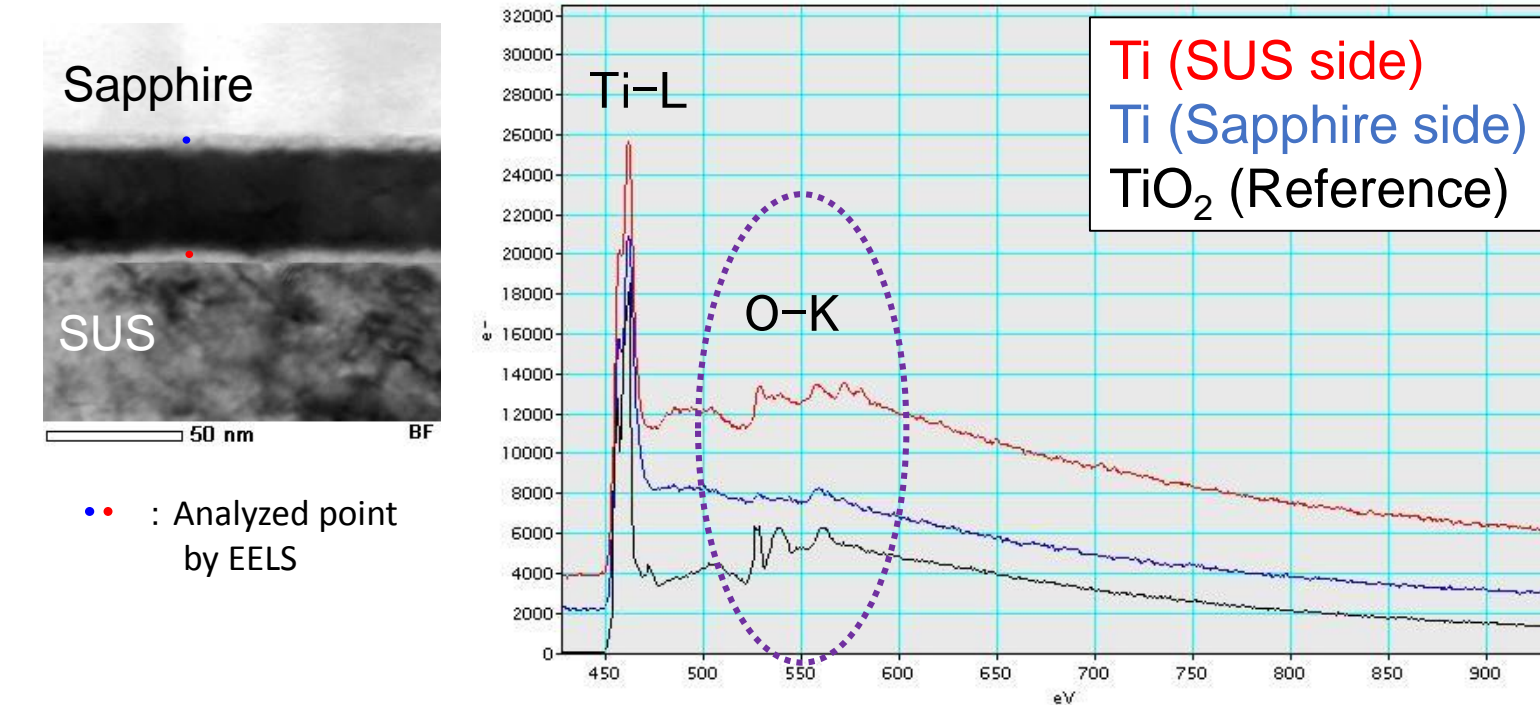


Figure 10. EELS

- ◇ Spectrum peak of Ti ($L\alpha$) is observed in both Ti layers.
- ◇ Ti layer on the SUS side shows a clear peak of O ($K\alpha$), and its spectrum is similar to that of reference TiO₂.

Oxidization of the Ti layer on the SUS side is probably caused by the oxygen dissociated from the CrO₂ surface layer of SUS. Actually the free energy of formation of oxide compounds from Ti is smaller than that of Cr.

Bonding of sapphire and Al was also achieved.



Figure 11. Bonding sample (Al and sapphire)

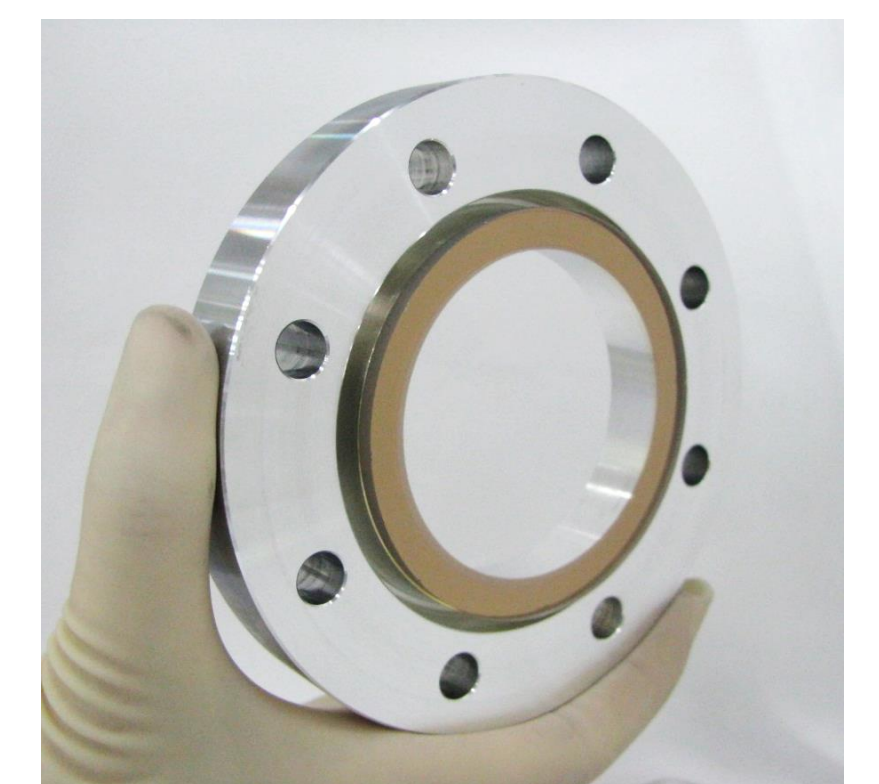


Figure 12. Viewing port (bonded Al and sapphire)

- Aluminum substrate $\phi 76 \text{ mm} - 8 \text{ mm}$
- Sapphire substrate $\phi 76 \text{ mm} - 0.55 \text{ mm}$
- Bonded area: 45.37 cm^2

- Bonding area of the Al flange $\phi 70 \text{ mm} - \phi 58 \text{ mm} - 8 \text{ mm}$
- Sapphire substrate $\phi 70 \text{ mm} - 3 \text{ mm}$
- Bonded area: 12.06 cm^2

5. Summary

- ◇ Room temperature bonding of sapphire with sapphire and metals (SUS, Al) was achieved using Au films in air with reliable bonding strength.

- ◇ The bonding technique can support expansion of the potential applications of sapphire in diverse industries.